



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: John L. Fulton, et al.

Serial No: 10/783,249

Filed: 2/19/2004

For: PROCESS AND APPARATUS FOR  
REMOVING RESIDUES FROM  
SEMICONDUCTOR SUBSTRATES

) Art Unit: 1746

) Examiner: Michail Kornakov

) File No: 14138-J

) Date: February 8, 2005

INFORMATION DISCLOSURE STATEMENT

(References – See attached forms PTO/SB/08A and PTO/SB/08B)

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Commissioner for Patents  
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Alexandria, VA 22313-1450

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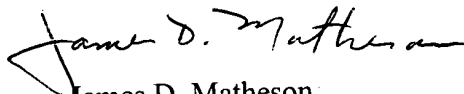
Attached hereto are Forms PTO/SB/08A and PTO/SB/08B listing documents believed to be relevant to the subject application. It is respectfully requested that these documents be considered by the examiner and an initialed copy of each form be returned to the undersigned.

This disclosure statement should not be construed as a representation that a search has been made or that no other material information exists, as defined in 37 C. F. R. § 1.56(a). No admission is made regarding whether any of the submitted references is prior art.

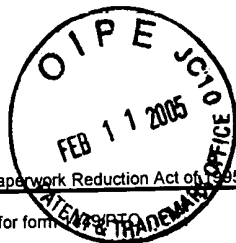
It is believed that this disclosure complies with the requirements of 37 C. F. R. §§ 1.56, 1.97, 1.98, and the Manual of Patent Examining Procedures § 609. If for some reason the examiner considers otherwise, it is respectfully requested that the undersigned be called so that any deficiencies can be remedied.

This IDS is either being submitted within the 3 month deadline or prior to the 1<sup>st</sup> Office Action, and no fees are believed to be required. However, if any fees are required for consideration of this paper, the Director is hereby authorized to charge our Deposit Account No. 02-1275.

Respectfully submitted,

  
James D. Matheson  
Reg. No. 54,569

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PTO/SB/08A (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

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Sheet

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of

9

**Complete if Known**

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Filing Date	02/19/2004
First Named Inventor	John L. Fulton
Art Unit	1746
Examiner Name	Michail Kornakov
Attorney Docket Number	14138-J

**U. S. PATENT DOCUMENTS**

Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
		US- 5,470,802	11-28-1995	Gnade et al.	
		US- 5,488,015	01-30-1996	Havemann et al.	
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**FOREIGN PATENT DOCUMENTS**

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		Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)				
		JP02001122	6/9/1988	Matsushita Elec		
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		JP03261128A2	03/09/1990	Sumitomo Seika		

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Sheet 2 of 9**Complete if Known**

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Examiner Name	Michail Kornakov
Attorney Docket Number	14138-J

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		EP 0 687 004 A1	12-13-1995	Chih-Chen Cho		
		EP 0 688 052 A3	08-28-1996	Shin-Puu Jeng		

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Sheet 3 of 9

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Attorney Docket Number	14138-J

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		EP 1 024 524 A2	01-25-2000	Kiyoyuki Morita		

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Date Considered

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STATEMENT BY APPLICANT**

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**Complete if Known**

Sheet 9 of 9

Application Number	10/783,249
Filing Date	02/19/2004
First Named Inventor	John L. Fulton
Art Unit	1746
Examiner Name	Michail Kornakov
Attorney Docket Number	14138-J

**NON PATENT LITERATURE DOCUMENTS**

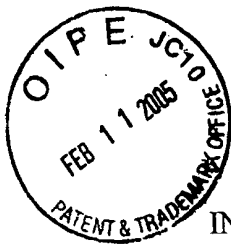
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Inventor: John L. Fulton, et al.

) Art Unit: 1746

Serial No: 10/783,249

) Examiner: Michail Kornakov

Filed: 2/19/2004

) File No: 14138-J

For: PROCESS AND APPARATUS FOR  
REMOVING RESIDUES FROM  
SEMICONDUCTOR SUBSTRATES

) Date: February 8, 2005

CERTIFICATE OF MAILING

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